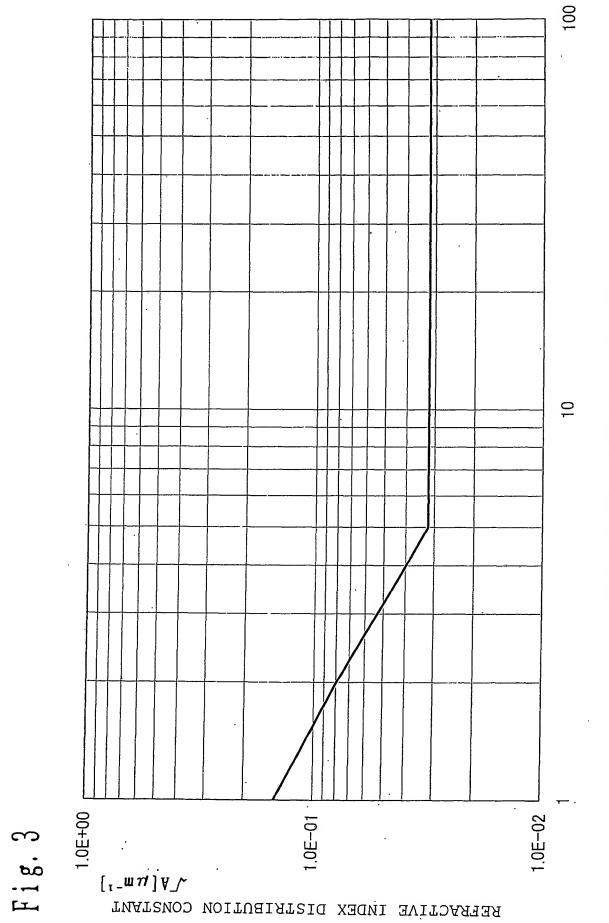
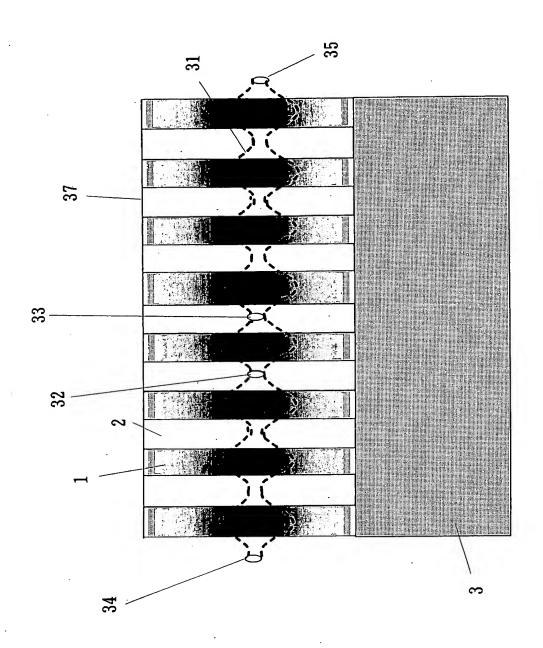
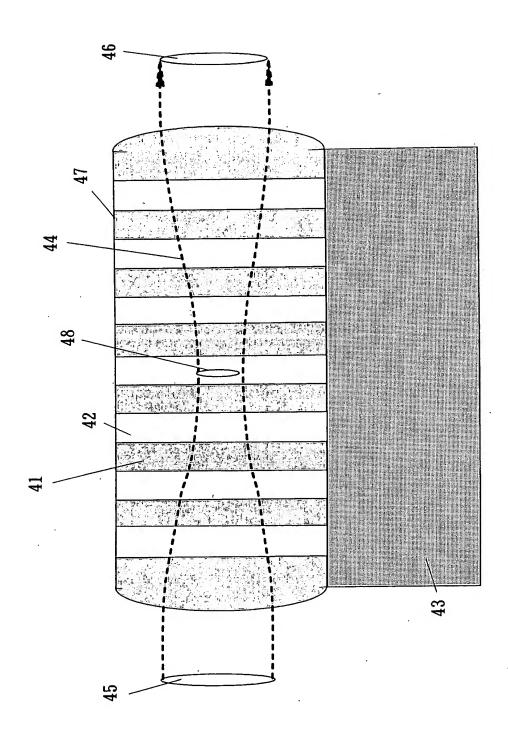


т. ос

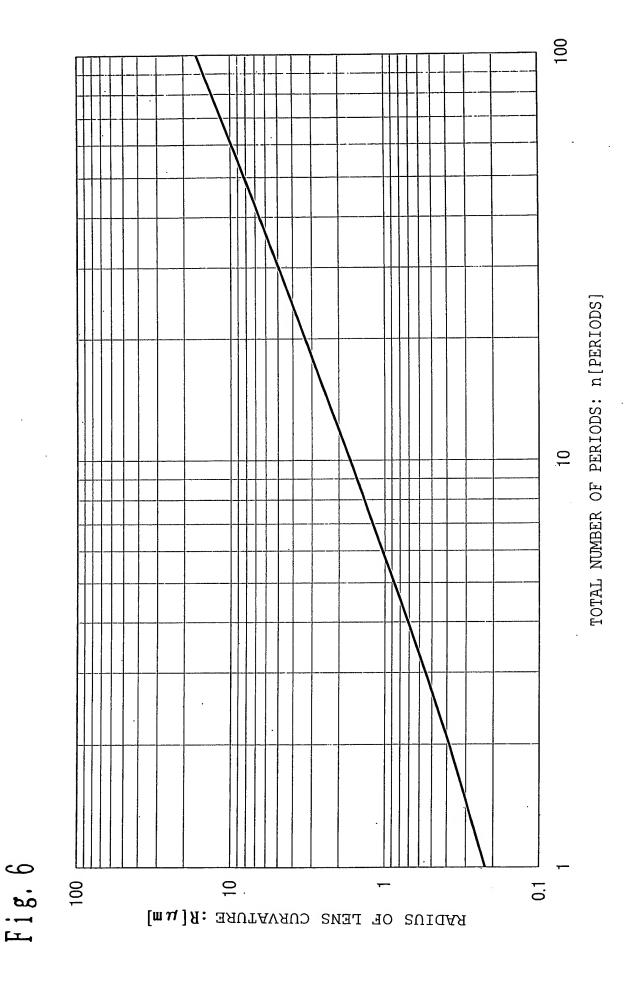


TOTAL NUMBER OF PERIODS n[PERIODS]





F1.00



F1.8

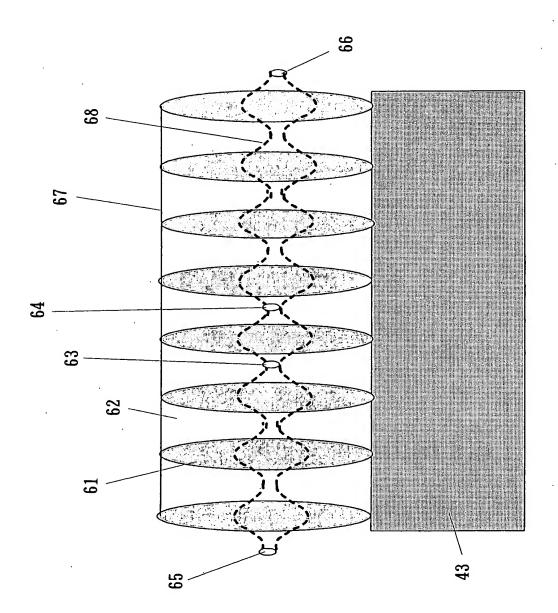


Fig. 8 (a)

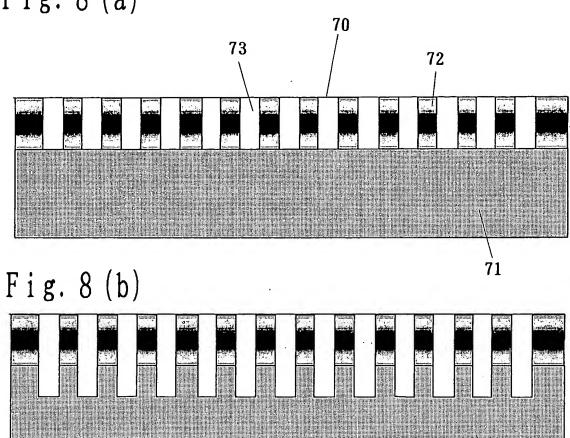
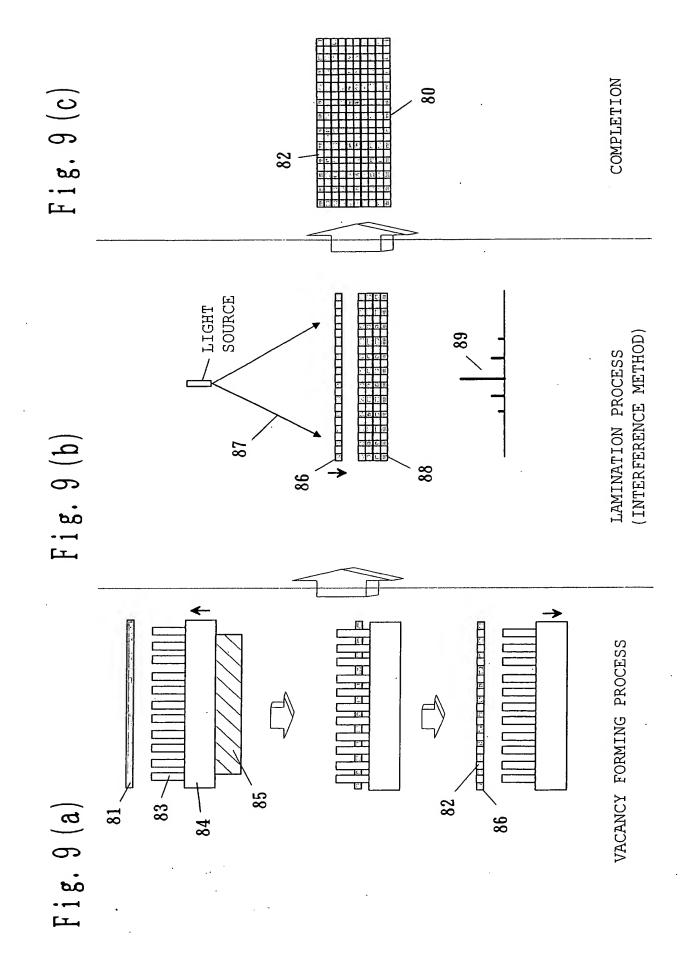


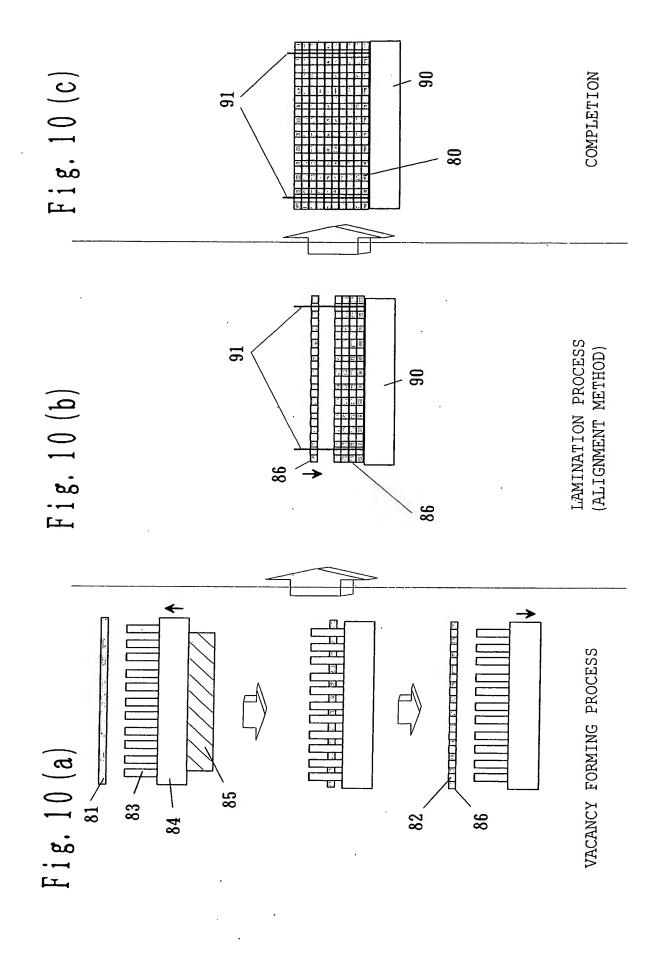
Fig. 8 (c)

75

72

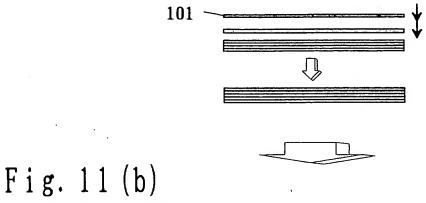
74



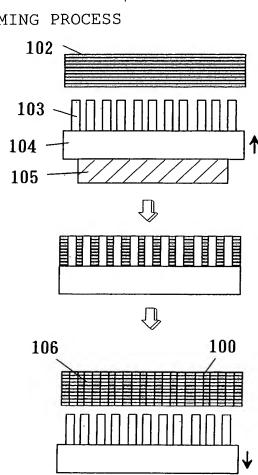


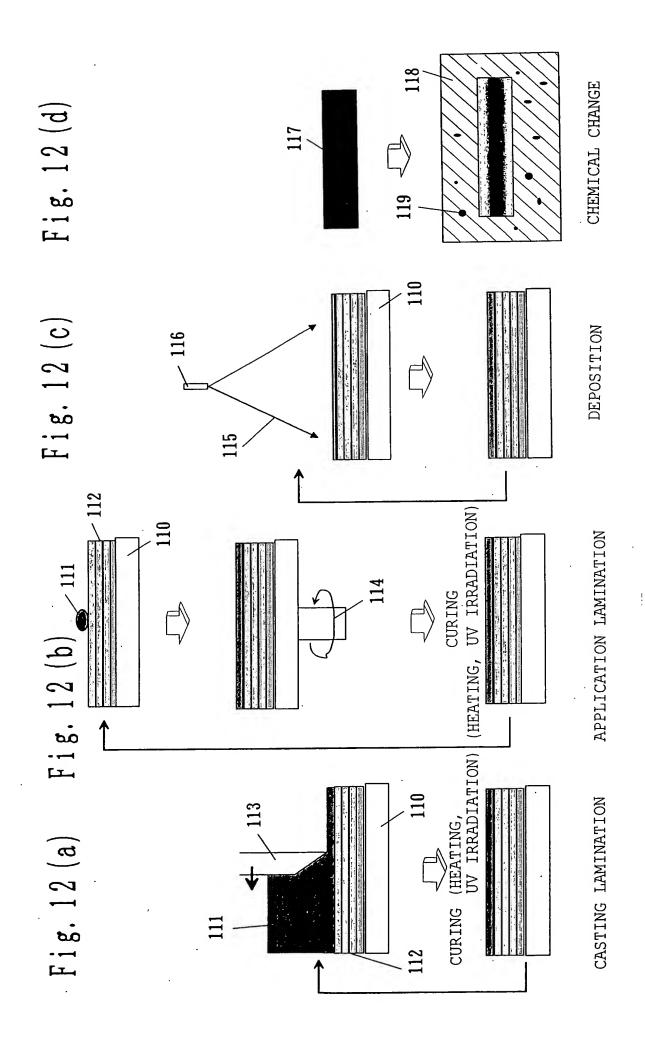
## Fig. 11 (a)

REFRACTIVE INDEX DISTRIBUTED FILM MAKING PROCESS



VACANCY FORMING PROCESS





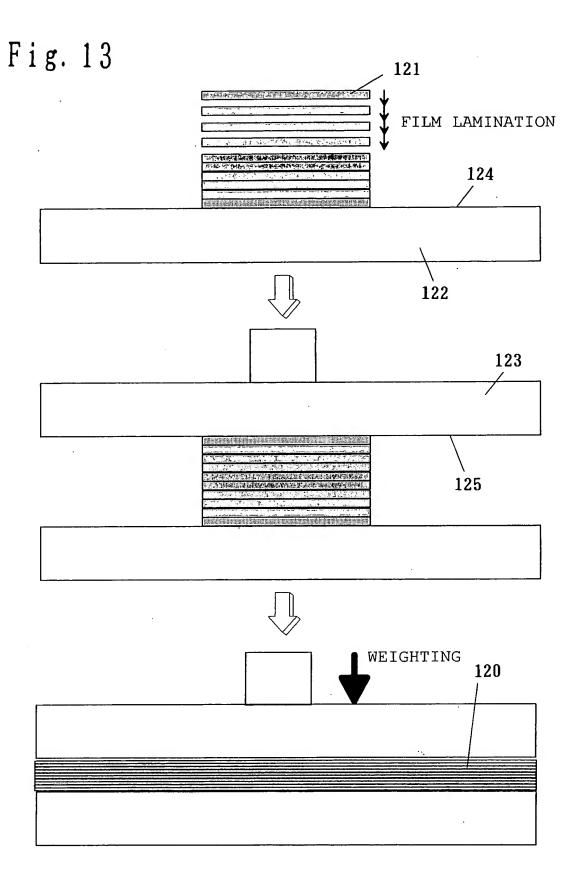
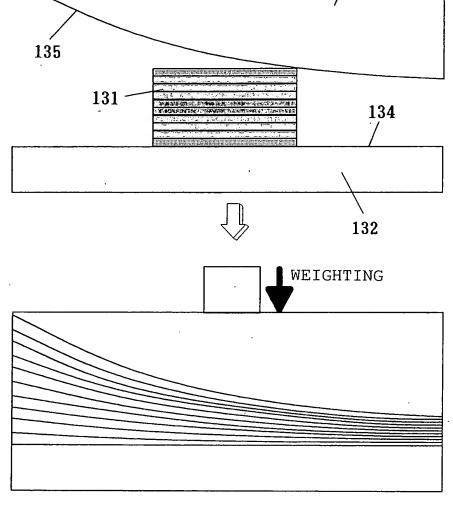


Fig. 14



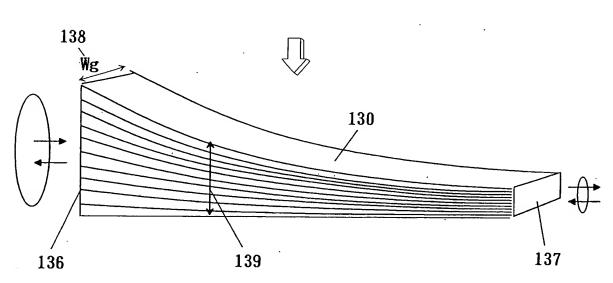
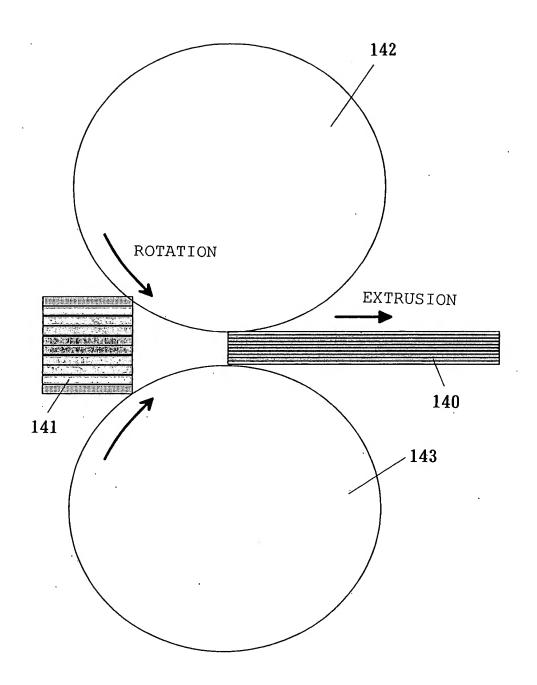
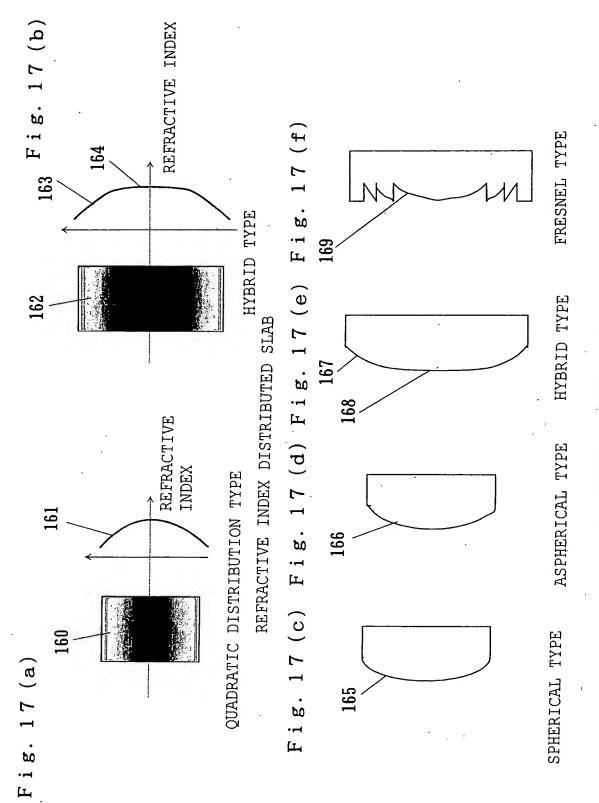


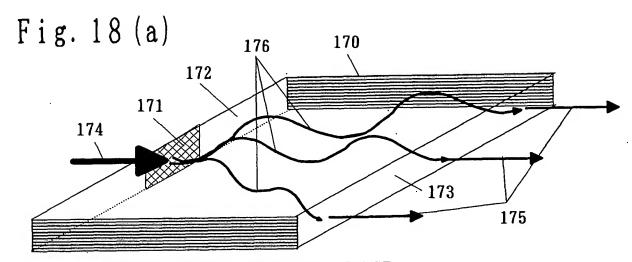
Fig. 15



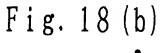
1 g 1 (

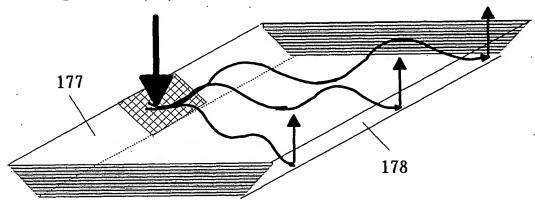


END SURFACE WORKED SLAB

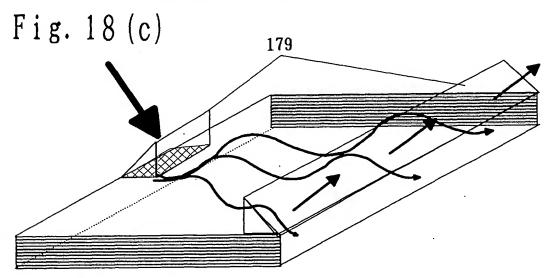


LINEAR-TYPE MULTICAST

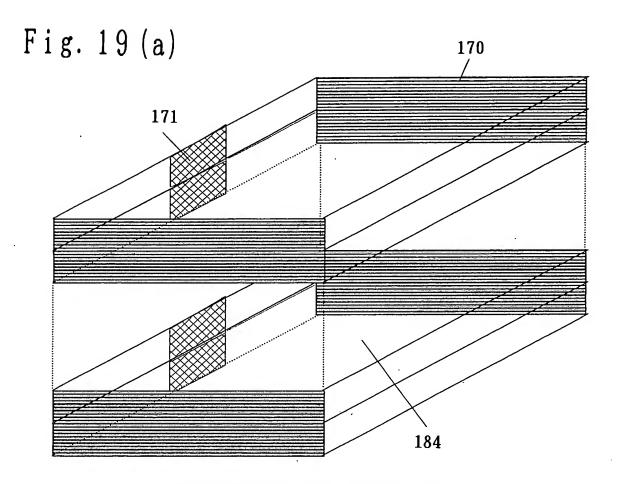




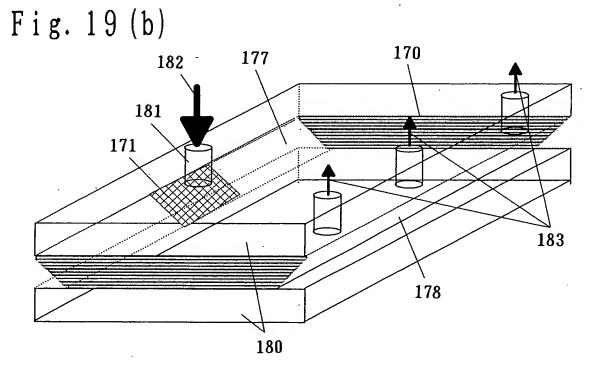
REFLECTION-TYPE MULTICAST



COUPLER-TYPE MULTICAST

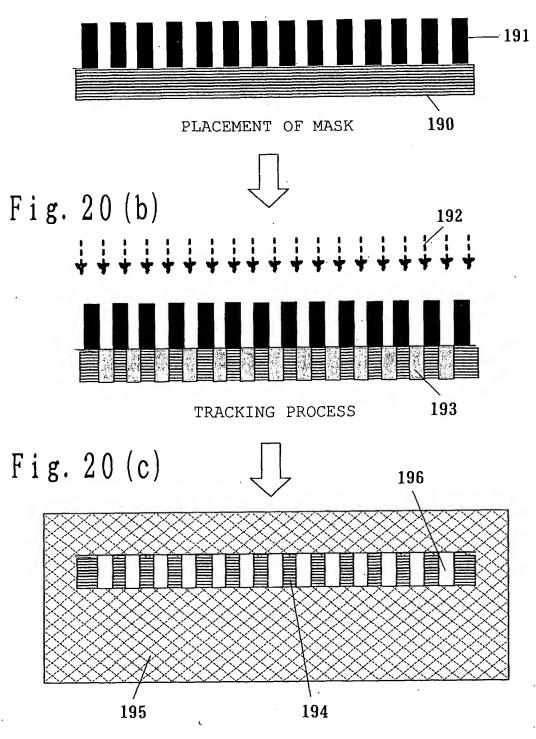


MULTILAYER SLAB WAVEGUIDE



HYBRID WAVEGUIDE

Fig. 20 (a)



ETCHING PROCESS

